

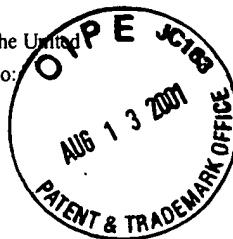
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On August 9, 2001

TOWNSEND and TOWNSEND and CREW LLP

By: [Signature]



PATENT
1084D01T9320
016301-009320

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

David Cheung et al.

Application No.: 09/418,818

Filed: October 15, 1999

For: METHOD AND APPARATUS FOR
DEPOSITING ANTIREFLECTIVE
COATING

Examiner: Rudy Zervigon

Art Unit: 1763

AMENDMENT

#8C
8/20/01
MW

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed May 9, 2001, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 1, lines 9-11, please replace the paragraph with the following paragraph:

This application is a divisional of U.S. Application No. 08/672,888, filed June 28, 1996, which is a continuation-in-part patent application of U.S. Application No. 08/567,338, filed December 5, 1995, entitled "Anti-Reflective Coating and Method for Depositing Same."

IN THE CLAIMS:

Please amend claims 1, 3, 44, and 60-62. The remaining claims are unamended, but are reproduced below for the Examiner's convenience and reference.

1. A substrate processing system, comprising:

C2
[Signature]